

Application No.: 10/623,958  
Date of Response: 09/02/2004  
Reply to Action of: 08/20/2004

Application No.	10/623,958
Applicant	Mandina, Michael P.
Filed	8/20/2004
Title	Apparatus and Process for Polishing a Substrate
TC/A.U.	3723
Examiner	Rachuba, Maurina T
Docket No.	MPM-560

Honorable Commissioner for Patents  
P.O. Box 1450  
5 Alexandria, VA 22313-1450

RECEIVED  
CENTRAL FAX CENTER  
SEP 02 2004

### ELECTION

Sir:

In reply to the Office Action of August 20, 2004, please find the response  
10 as follows:

**Election** begins on page 2 of this paper.

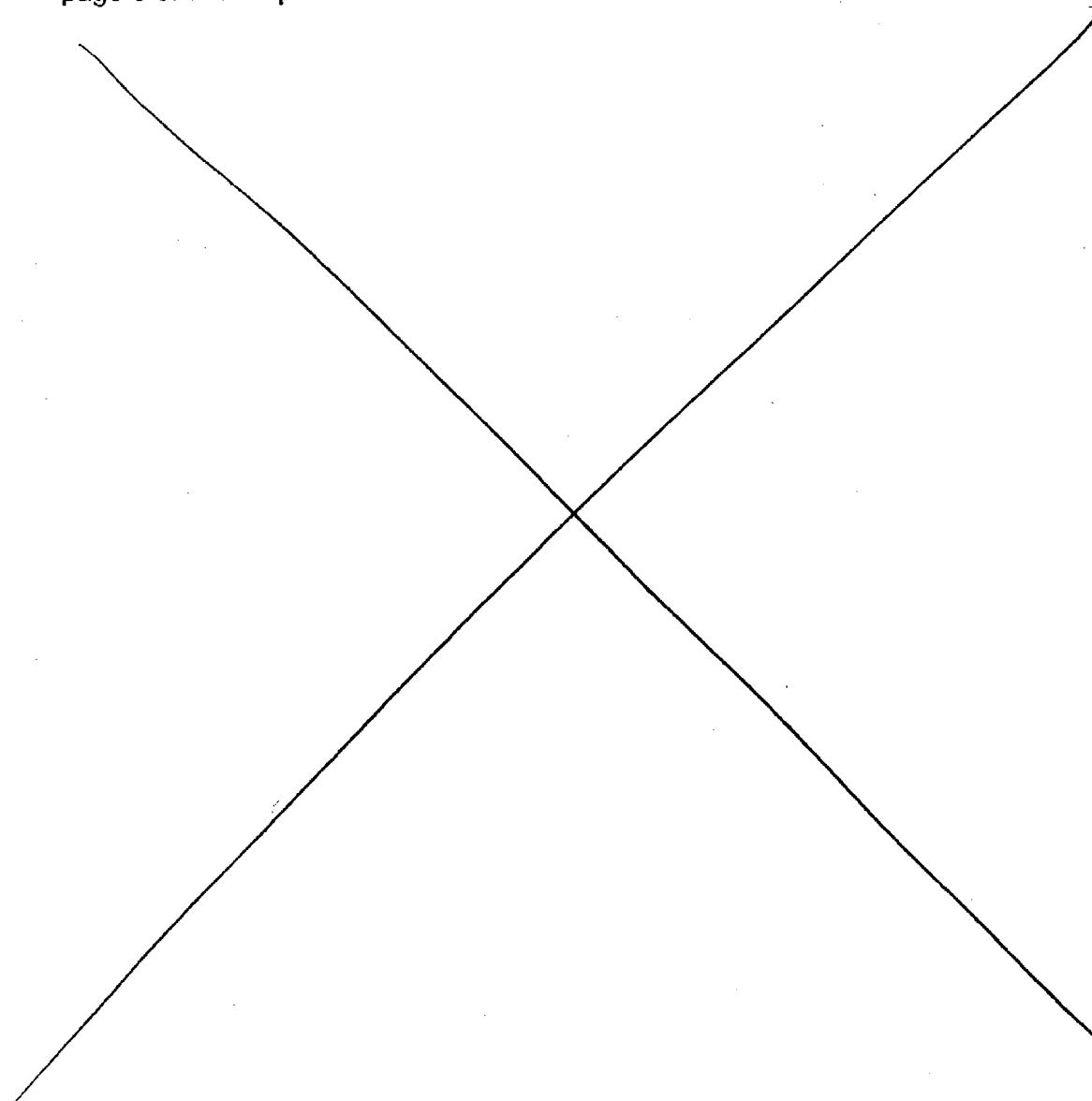
**Remarks/Arguments** begin on page 3 of this paper.

Application No.: 10/623,958  
Date of Response: 09/02/2004  
Reply to Action of: 08/20/2004

## ELECTION

In response to the Office Communication of August 20, 2004, in which the Examiner requested election of species for prosecution on the merits, applicant provisionally elects Species 2 (means for moving the polishing pad in a linear motion), claims 1-20 with traverse.

The bases for the applicant's traverse of the Examiner's restriction requirement are respectfully submitted in the Remarks section beginning upon page 3 of this response.



Page 2 of 6